



ETHOS

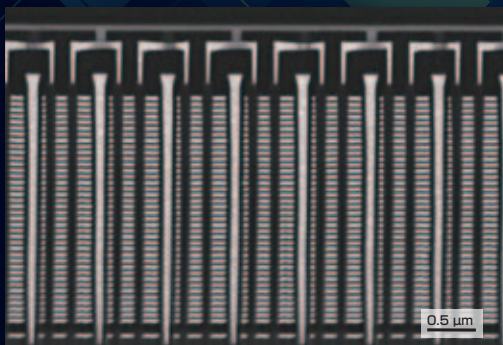
High-Performance Composite FIB-SEM System

- High-intensity CFE source and magnetic/electrostatic compound lens
- SEM column fitted with multi detectors
- Rapid processing due to FIB with high current density (Max. ion beam current : 100 nA)
- High-volume sample chamber for varied applications also fitted with stage offering high stability
- High-grade TEM sample preparation possible with Micro Sampling* and Triple Beam system**.

※ optional

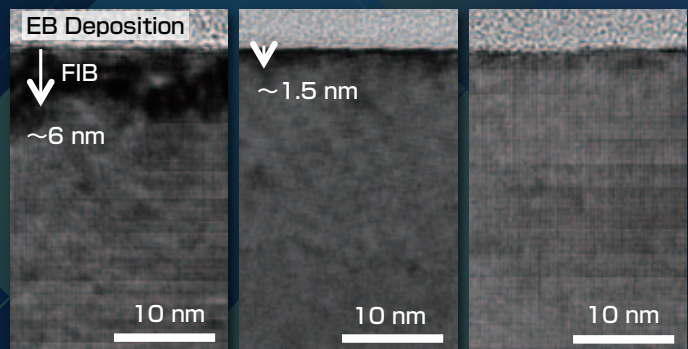


Observation



3D NAND device cross-section SEM image

Triple-Beam effect



(a) 5 kV Gallium ion milling

(a) 1 kV Gallium ion milling

(c) 1 kV Argon ion milling

High-resolution TEM images of GaN crystal on the <1-100> axial illumination
1 kV Argon ion milling preserve crystallinity to the surface